

09/926243

1616 Rec'd PCT/PTO SEP 28 2001

L. Nelson
#3/Pre Amdt A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE 11-30-01

In re application of:

KIUCHI et al.

Group Art Unit:

Serial No.: New Application

Examiner:

Filed: September 28, 2001

Docket No. P107242-00023

For: POLISHING APPARATUS AND METHOD

PRELIMINARY AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

September 28, 2001

Sir:

Prior to calculation of the filing fee and prior to the examination of this application, please amend the above-identified application as follows:

IN THE CLAIMS:

Please cancel original claims 1-31 and add the following claims.

A1
Sub B1
✓

-- 32. (Added) A polishing apparatus comprising:
a polishing table; and
a work holding plate,
wherein a work held on the work holding plate is polished supplying a
polishing agent solution, and in polishing action, an amount of deformation of the polishing
table in a direction normal to an upper surface thereof and/or an amount of deformation of
the work holding plate in a direction normal to a work holding surface thereof is restricted to
100 μ m or less.